

[54] **METHOD FOR AUTOMATIC ANALYSIS OF ELECTRON BEAM DIFFRACTION PATTERN**

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[58] **Field of Search** **250/306, 307, 311, 357, 250/252.1; 378/70, 71**

[56] **References Cited**

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[57] **ABSTRACT**

A video image of an electron diffraction pattern is digitized and captured as a two dimensional array of intensity values. From the array of intensity values, the frequency distribution of said intensity values is obtained. It is determined that the diffraction pattern is composed of only diffraction spots, only diffraction rings, or both diffraction spots and rings by analyzing said frequency distribution. The diffraction pattern is thus analyzed easily and automatically.

5 Claims, 21 Drawing Figures

